



Introduction to **M**ADEin4

Metrology Advances for Digitized ECS Industry 4.0

Olaf Kievit, TNO
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SEMICON Europa, EU Digital Future Forum

AGENDA

MADEin4 Project Essentials

Objective and Industry 4.0 boosters

Automotive and Semiconductor domains analogy

**Data is the new oil: design, modeling, metrology and ML
Context creation**

Project Highlights

MADEin4 presentations @ SEMICON Europa

AGENDA

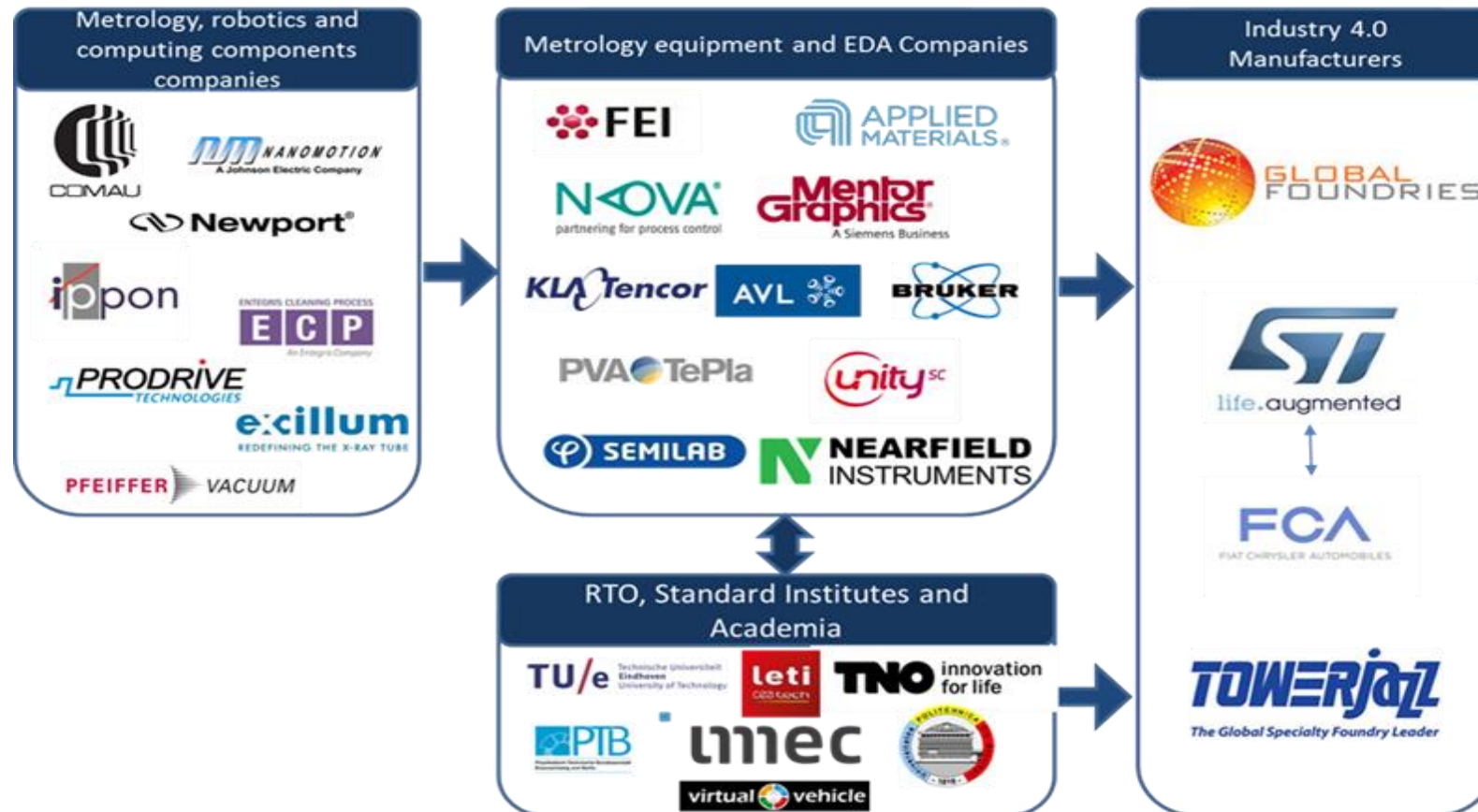
MADEin4 Project Essentials

Objective and Industry 4.0 boosters

MADEin4 project essentials

- Number of consortium members: 47
- Countries involved: 10
- Start date: April 1, 2019
- Duration: 36 months
- Total effort: person.months: 10,503 (875 person.years)
- Total H2020 eligible costs: € 126,176,472.50

MADEIn4 project essentials



Objective and Industry 4.0 boosters

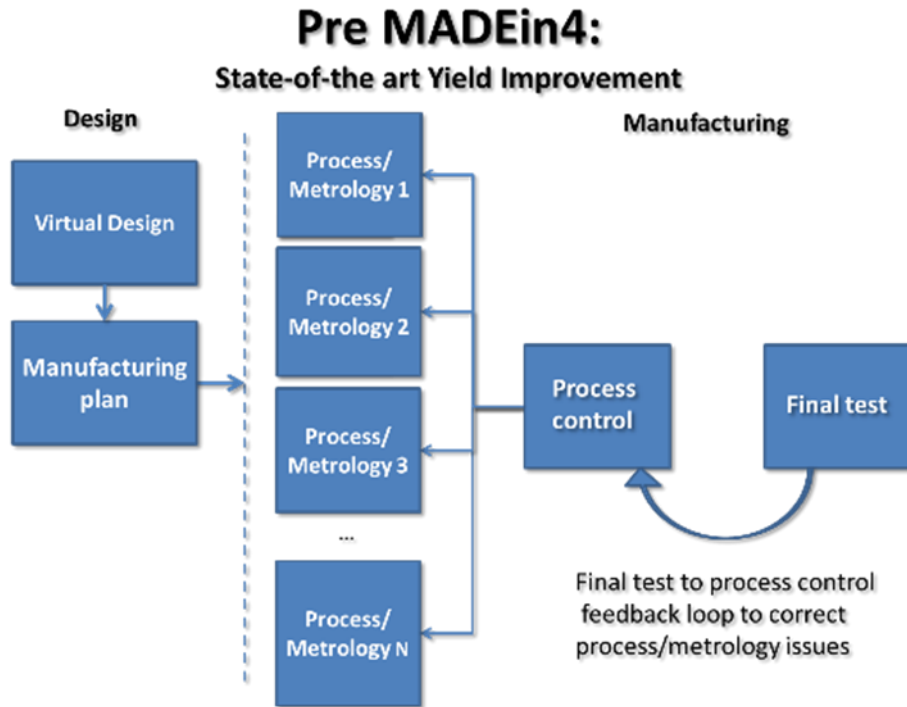
Develop and qualify new productivity boosters:

- Booster 1: High-productivity metrology and inspection tools for semiconductor and automotive industry
- Booster 2: Ready for “industry 4.0” Cyber Physical Systems (CPS):
 - Higher data rates and smart acquisition and processing
 - Smart use of data to improve the over-all productivity and predictability

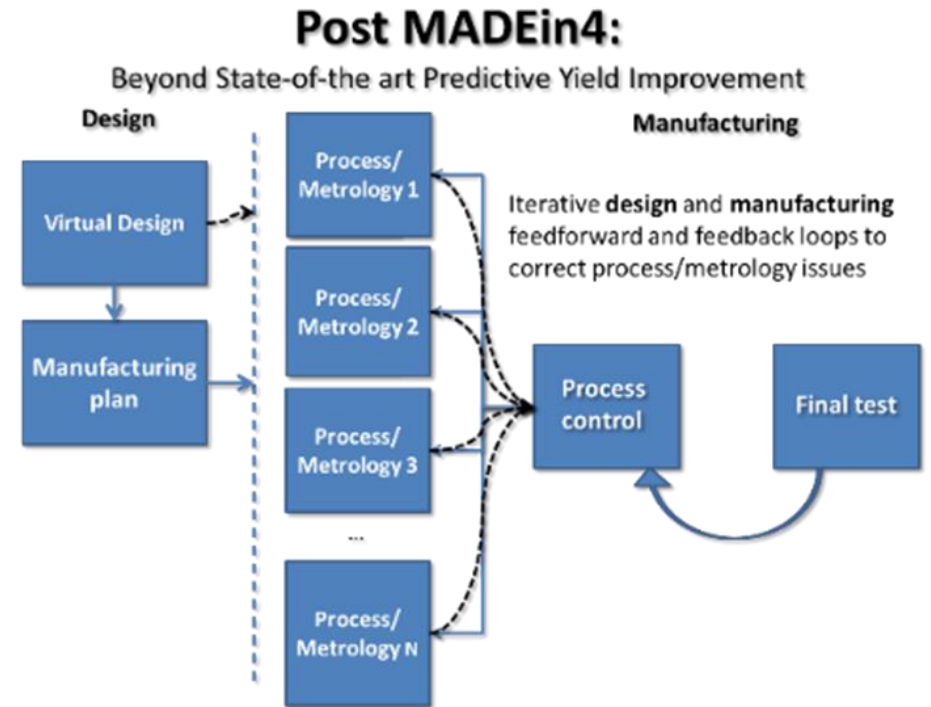
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Semiconductor and Automotive domains analogy

Semiconductor and Automotive domains analogy



From: reactive manufacturing

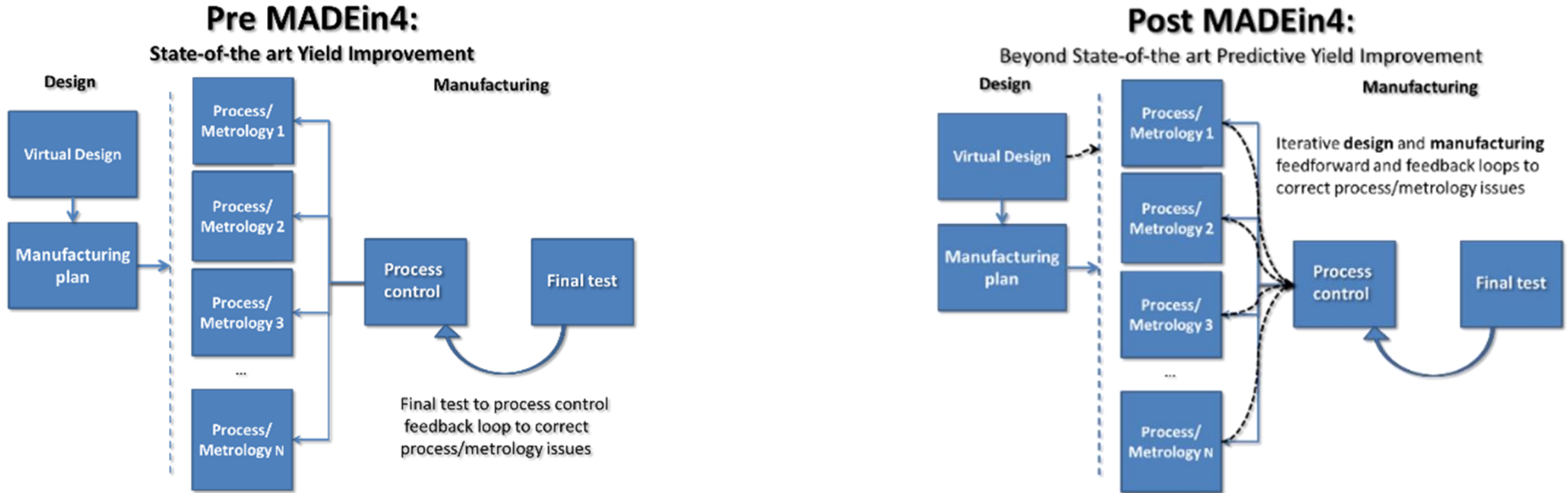


To: predictive manufacturing

Semiconductor and Automotive domains analogy

Semiconductor		Automotive
Number of measurements per wafer 10^3		Number of measurements per car $\gg 10^3$
Wafers per month $> 10^7$	Litho/ SEM	Doors welding/ Optical inspection
Number different products $10^2 < x < 10^3$		Number of different configurations $10^2 < x < 10^4$
Highly automated manufacturing	Etch/ SEM	Painting/ Optical inspection
Number of inputs per unit process (features) 10^2
Manufacturing process longevity much less than 10 years	CMP/ Reflectometry	Engines Assembly/ EOL hot test

Semiconductor and Automotive domains analogy



The Semiconductor and Automotive industries are sharing similar design and manufacturing flows and differ by the content of each of the design and manufacturing modules

This allows to develop innovative shared machine learning based methodologies which will enable the transformation of the manufacturing from reactive to predictive

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**Data is the new oil: design, modeling, metrology and ML
Context creation**

Data is the new oil

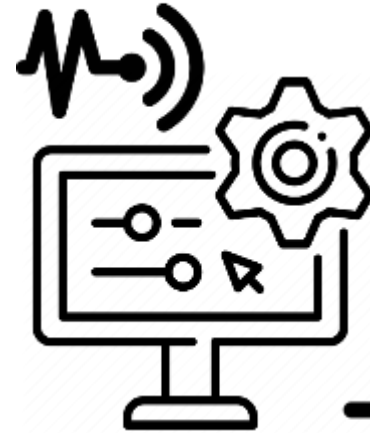
1

Data collected and pushed to the cloud



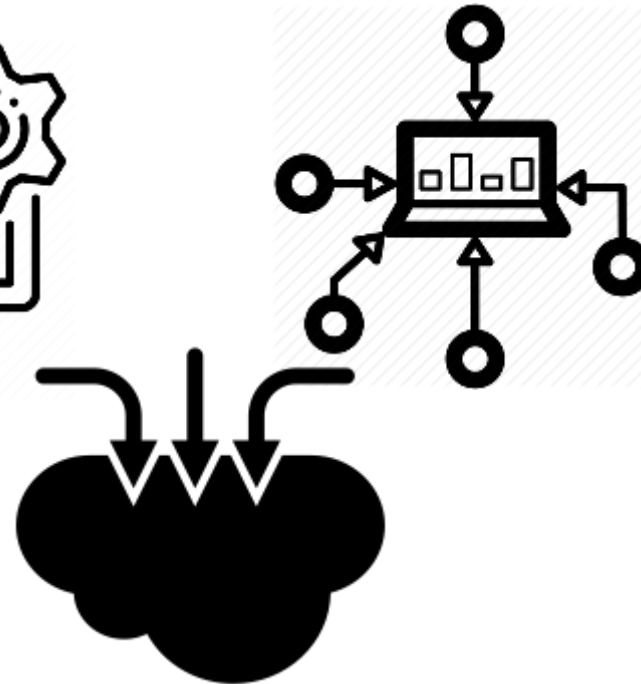
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Sensors are added to industrial computers



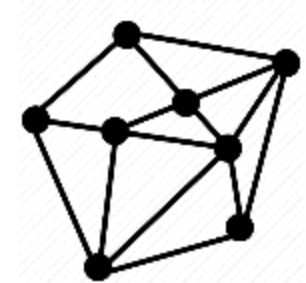
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Constant data collection for future possible usage

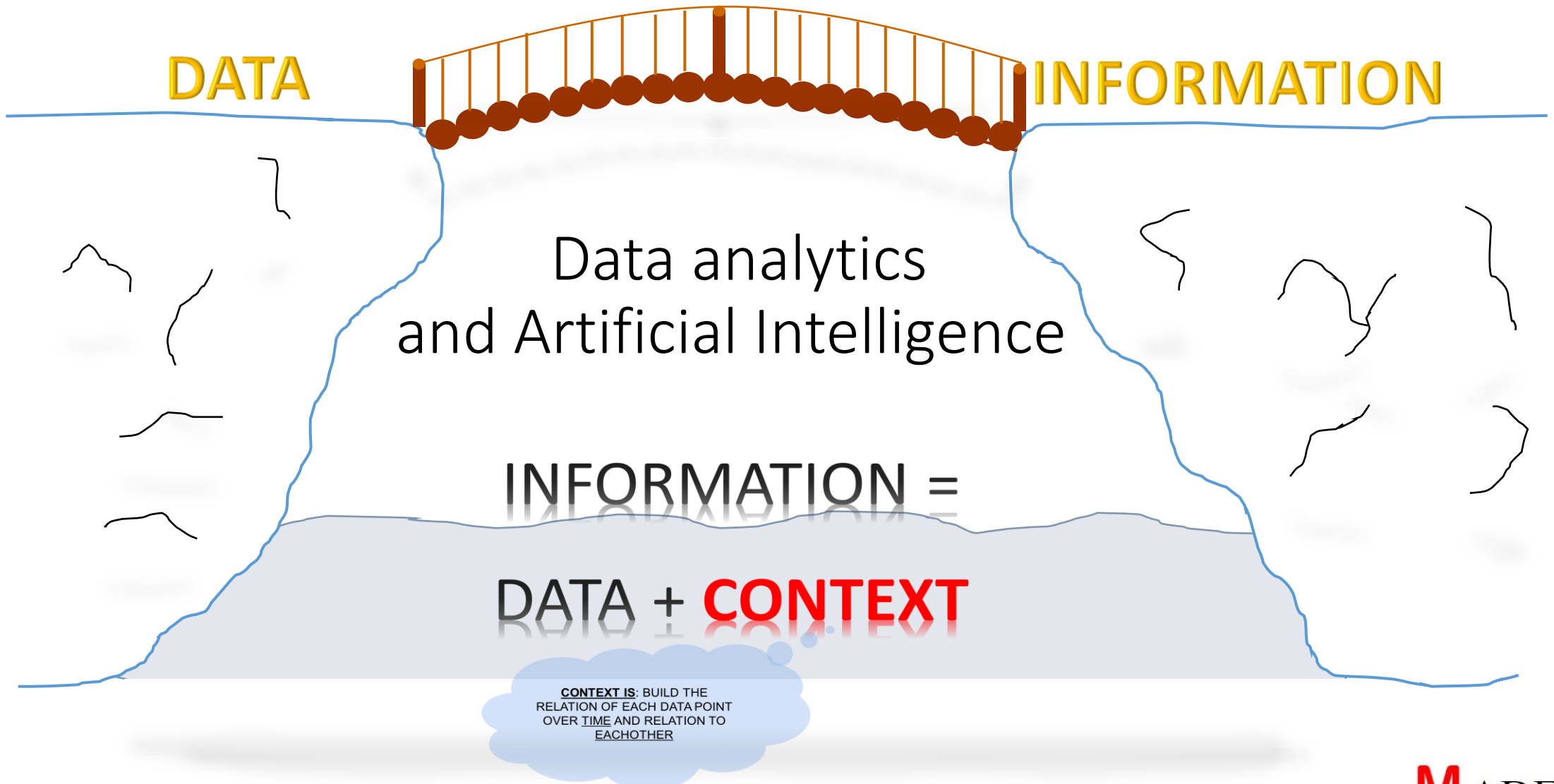


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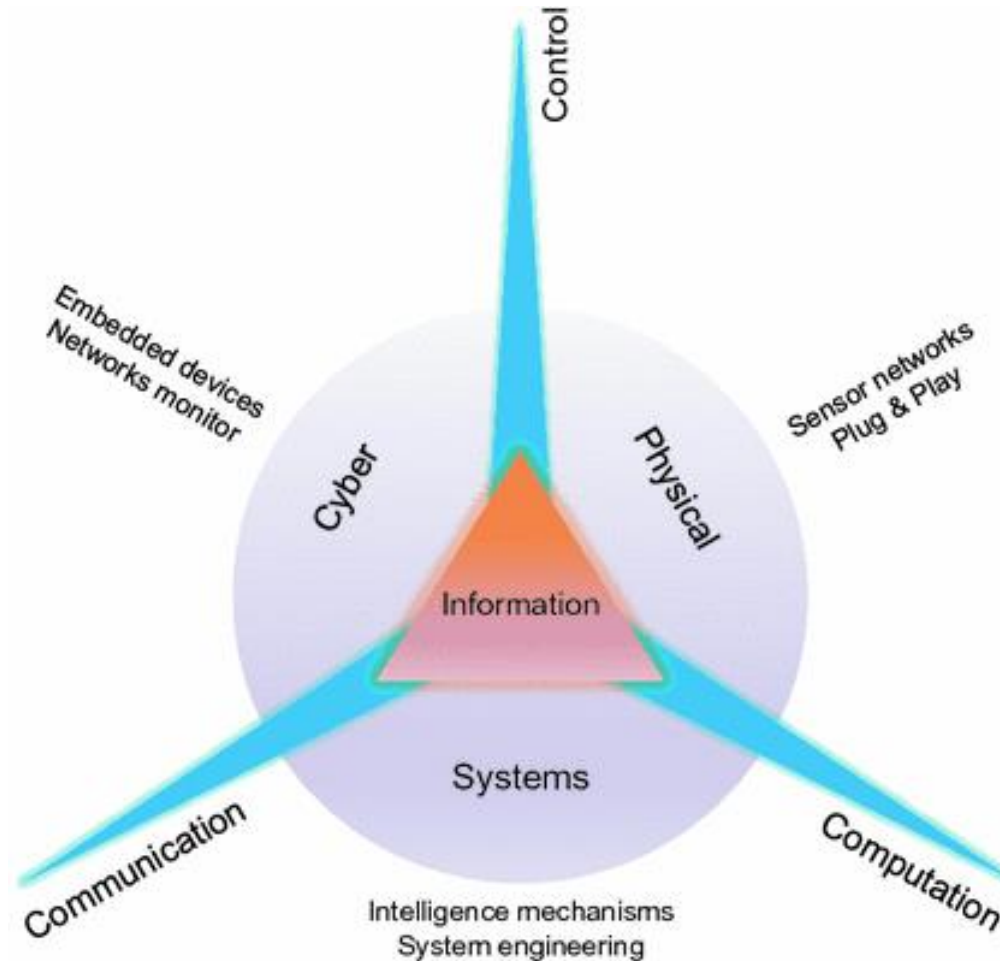
Data analysis by tailor-made algorithms



CONTEXT (crossing) the chasm

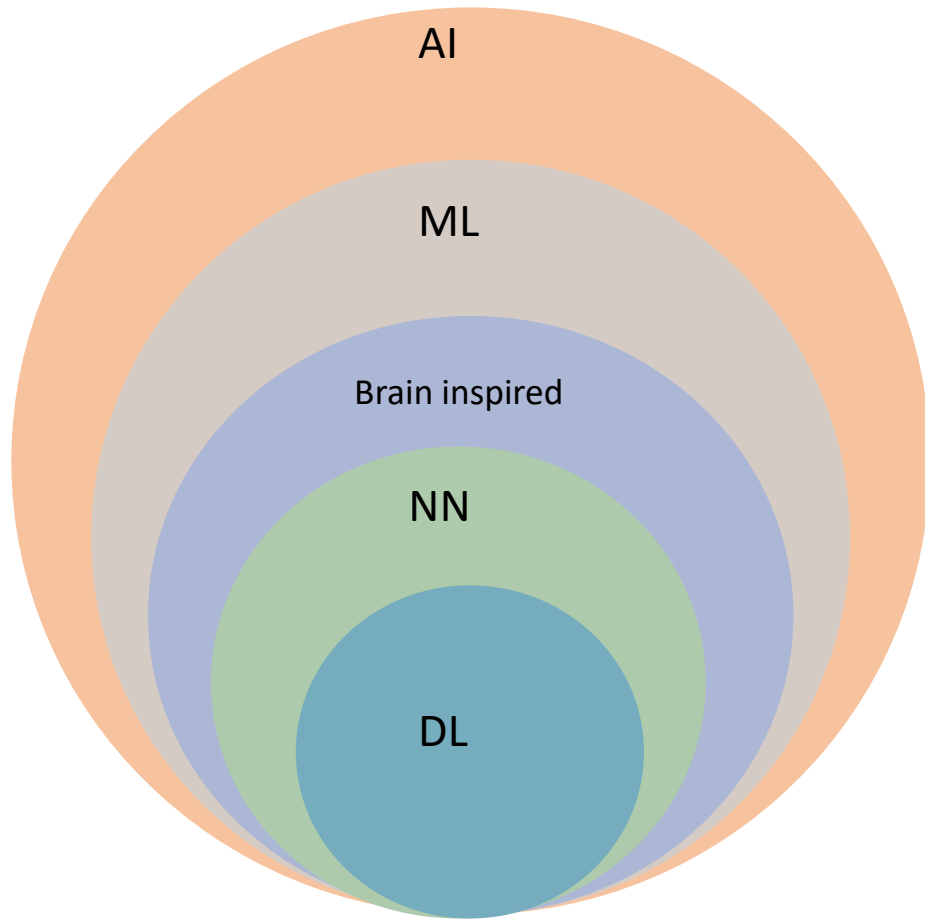


Cyber-physical Systems (CPS) for Information Creation



The interaction of physical and computing, including embedded intelligence at all levels

Artificial Intelligence (AI)



- AI: Artificial intelligence making decisions about a system
- ML: Machine learning modeling the behavior of a system
- NN: Neural networks are one implementation of machine learning
- DL: Deep learning is one implementation of Neural networks

Digital twinning: a virtual Representation of the Production Process

Traditional modeling: Physical models requiring little data but deep understanding of the process.

ML-based modeling: “black box” models requiring feature engineering coupled with sensor data.

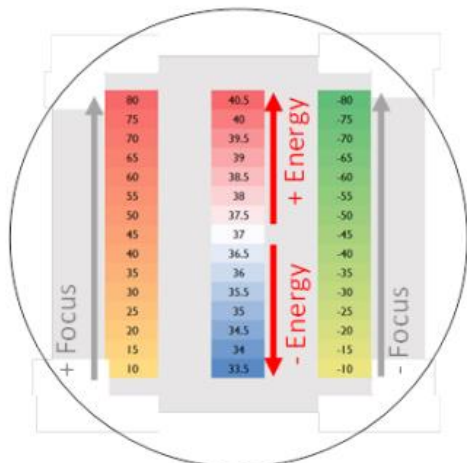


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Project Highlights

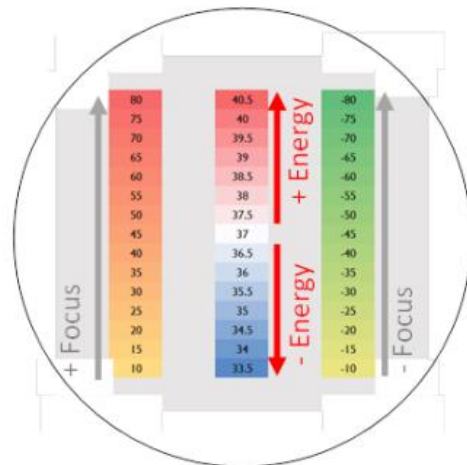
Imec created back end of line samples with special DoE for tools qualifications and predictive analytics activities

PW-M1- wafer



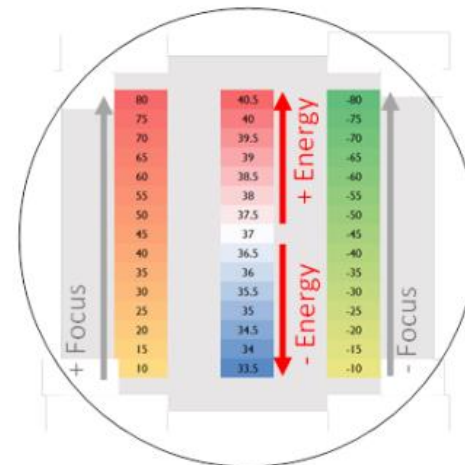
Typical modulations: focus, dose

PW-M2- wafer



Typical modulations: focus, dose

PW-Via- wafer



Typical modulations: focus, dose

Programmed Overlay

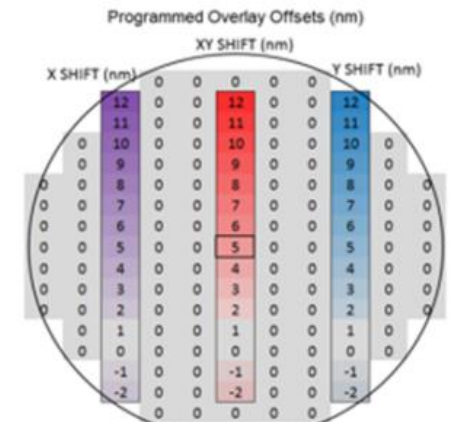


Figure 2

Excillum launched a first in a kind 700W MetalJet X-ray source prototype, increasing metrology tool throughput

MetalJet D2+ 250 W

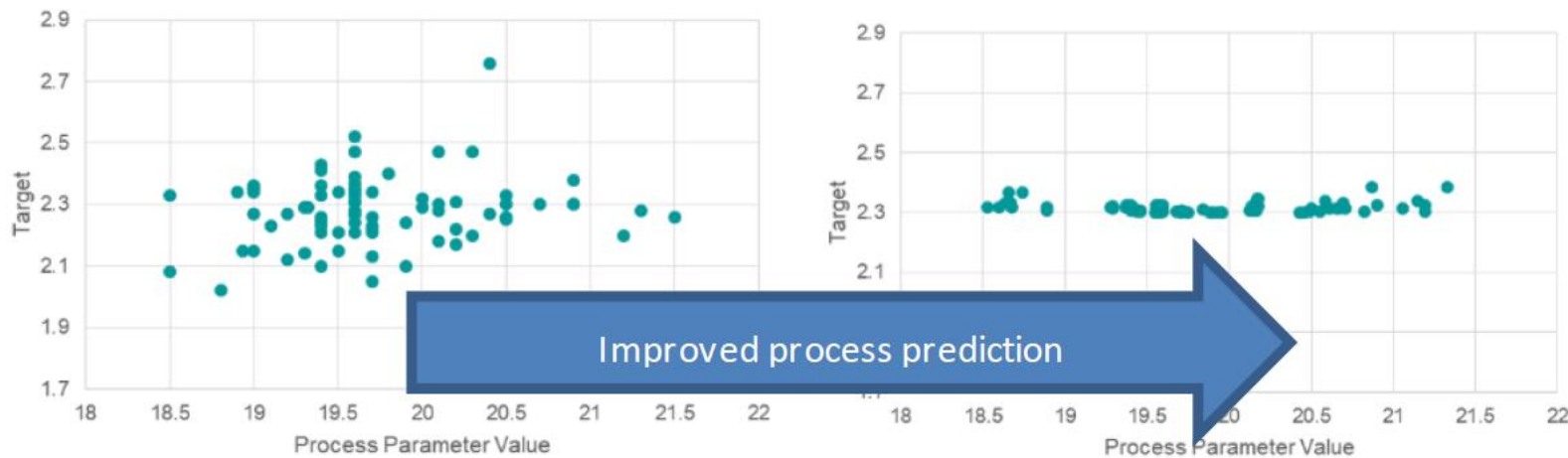
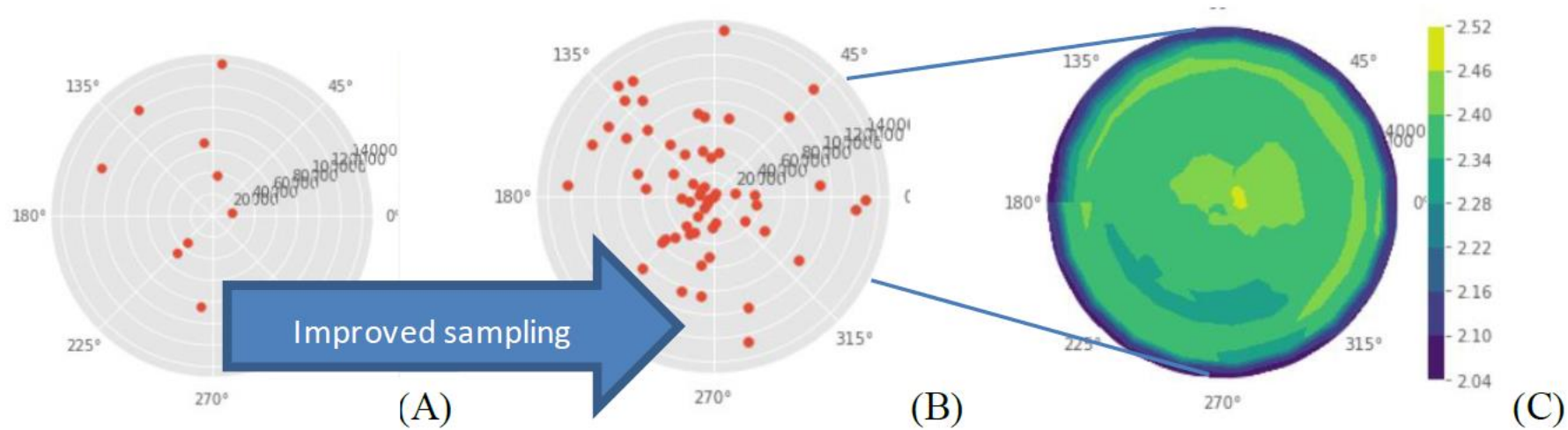


MetalJet E1 700 W

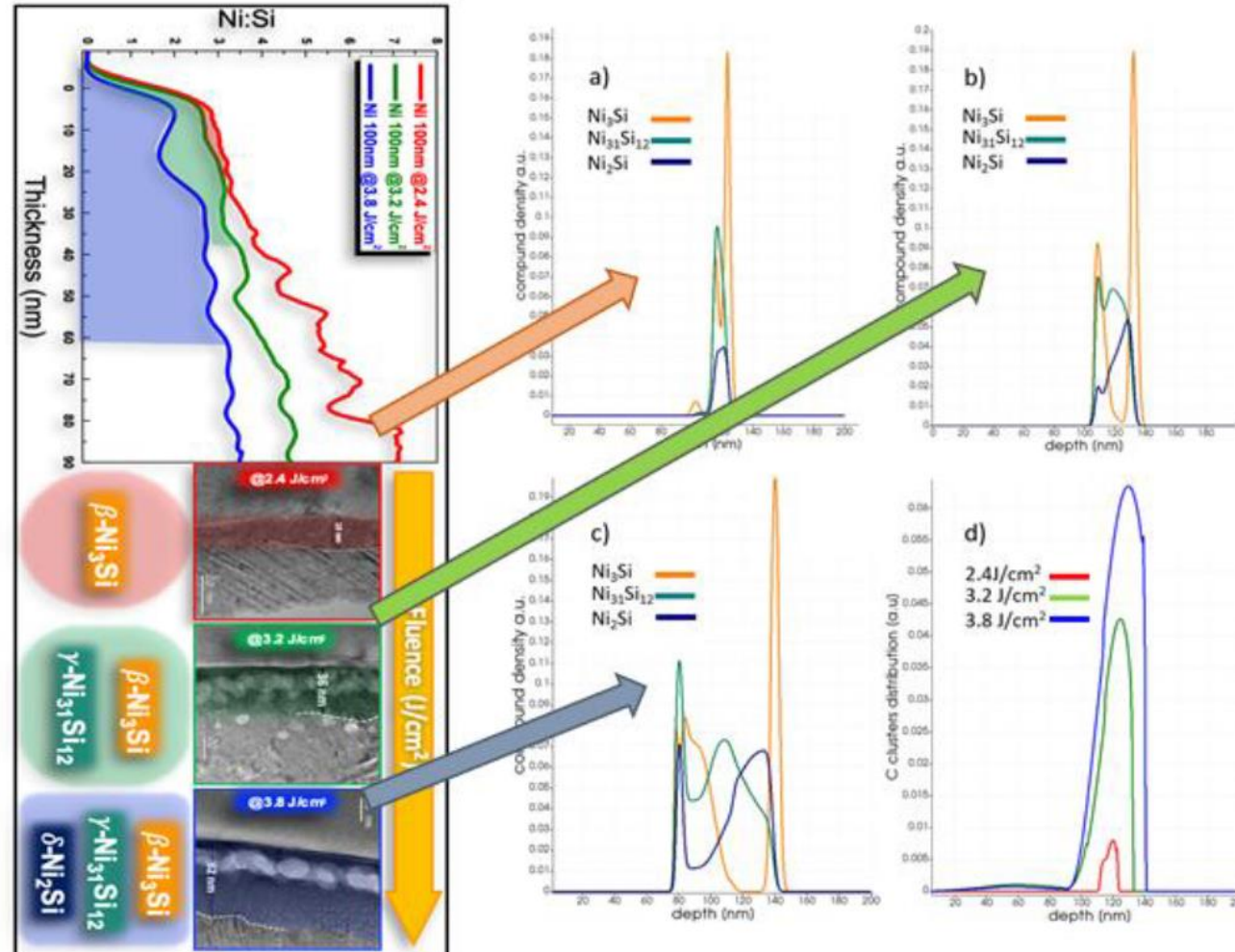


Highly synergetic
MetalJet E1 was
launched by
Excillum in July
2020!

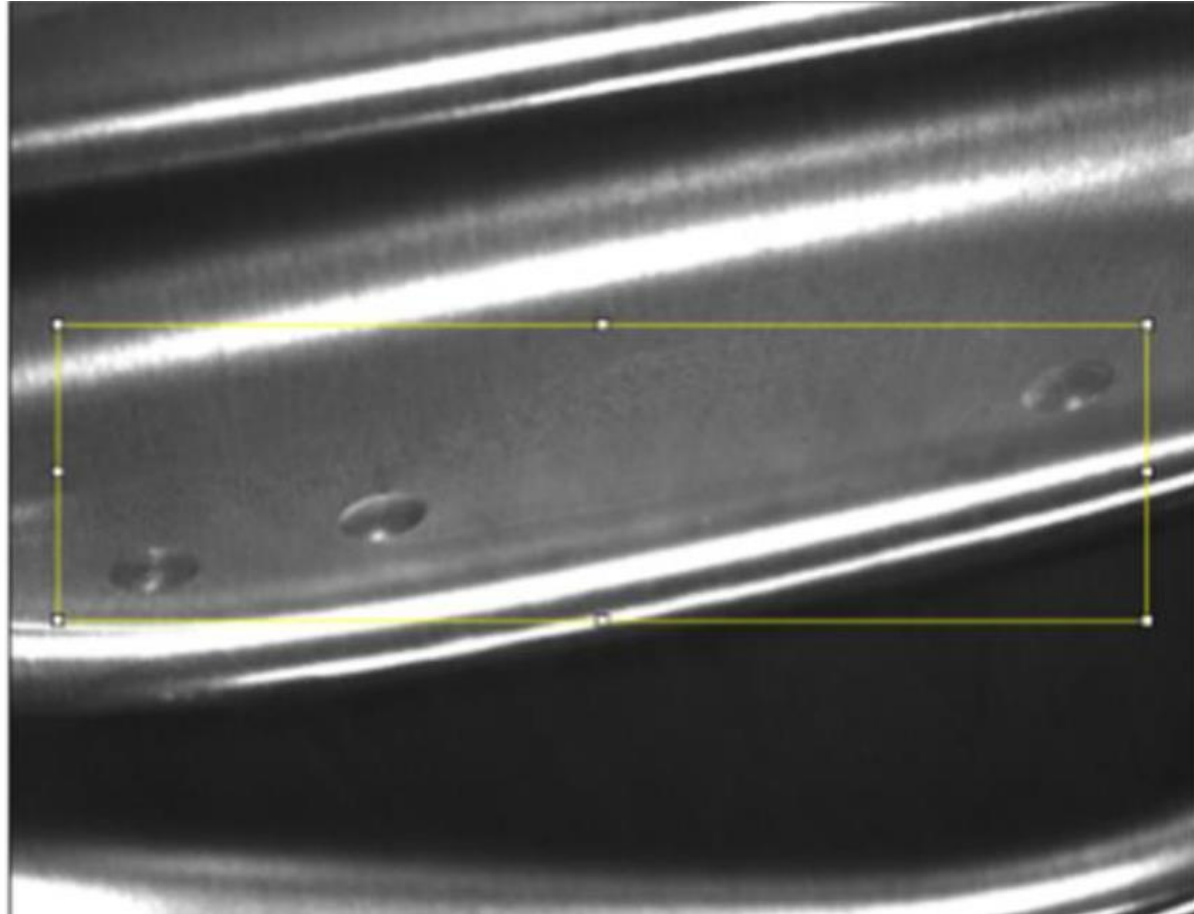
Mentor and GlobalFoundries demonstrated combined across wafer information



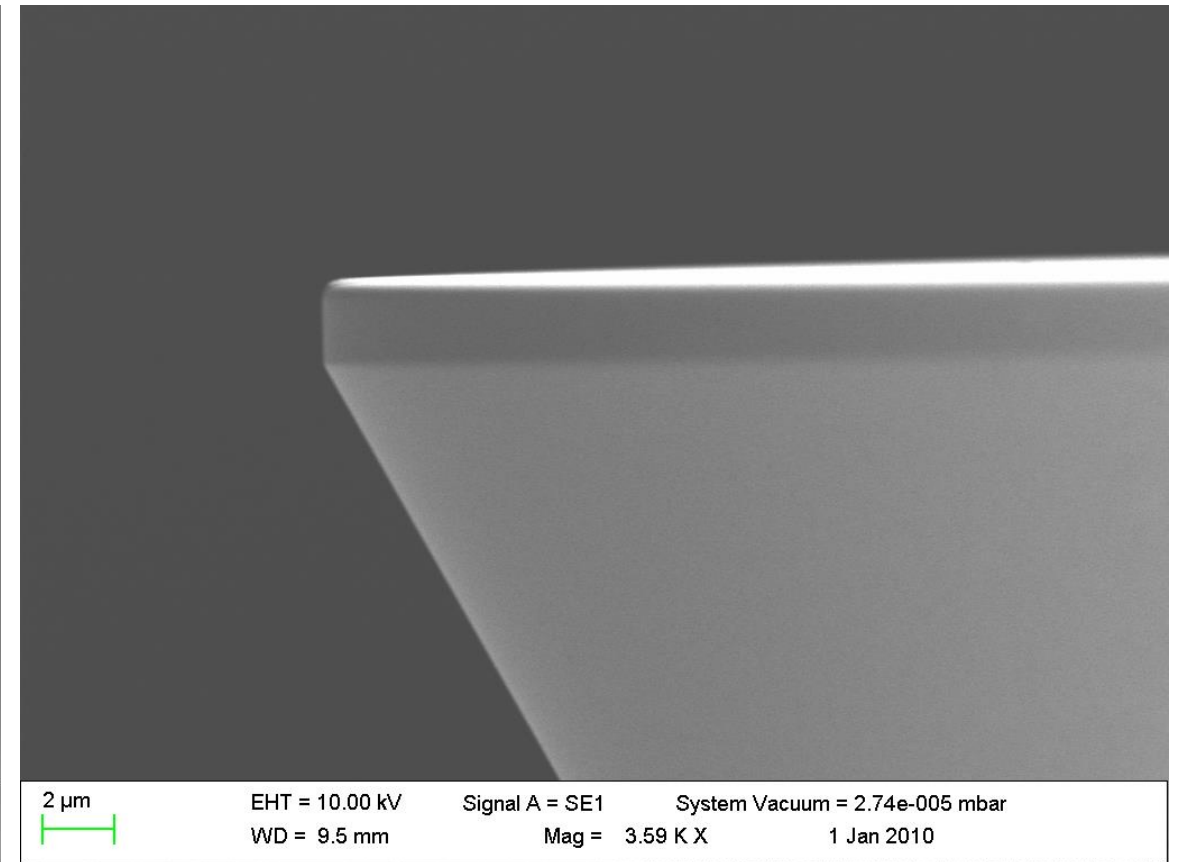
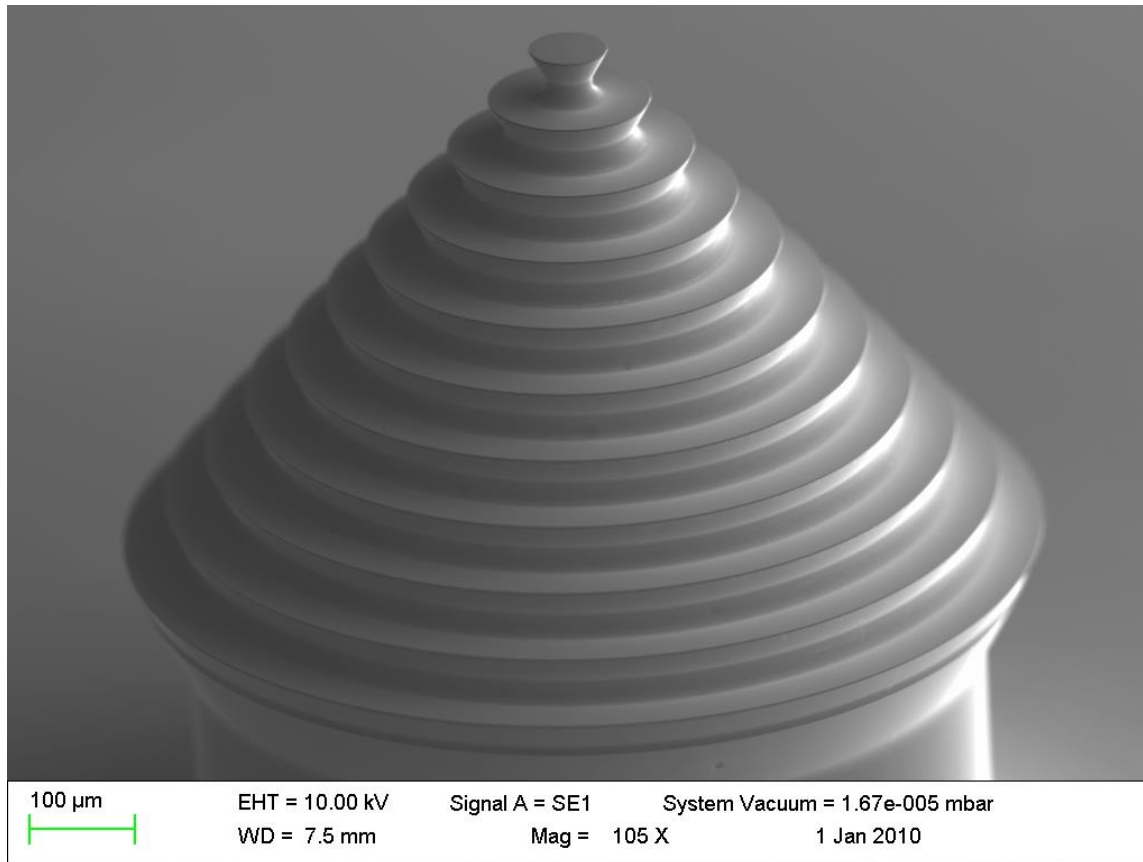
CNR, STMicroelectronics and UPB improved the simulation of laser annealing of Ni-SiC systems for back-junction formation, confirmed by TEM and XRD data



FCA, TOWER and TUD optimized the imaging conditioning for spot defects classification analysis in car doors welding



PTB created a prototype 3D metrology physical target to standardize probe-based microscope calibration



AGENDA

MADEin4 presentations @ SEMICON Europa

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MADEin4 Session 16. November 2021 / 10:00 – 11:30

From reactive to predictive: Smart Manufacturing in the Semiconductor Industry – The MADEin4 Initiative

- Simona Laza (Excillum) – MetalJet - a New Key Module for Enhanced Metrology Capabilities
- Juliette van der Meer (Bruker) – Advances in X-ray Metrology under MADEin4
- Thomas Ashby (imec) – Privacy Preserving Amalgamated Machine Learning (PAML) in the Fab, and machine learning workflow in the MADEin4 project

SMART X Session 17. November 2021 / 10:00 – 10:30

- Ovadia Ilgayev (NOVA) – Recent Innovations in Integrated Metrology

MADEin4 presentations @ SEMICON Europa

MADEin4 Session 19. November 2021 / 10:00 – 11:30

Artificial Intelligence and Robotics in the Semiconductor Industry: Manufacturing the Smart Way – The MADEin4 Initiative

- Jean Hervé Tortai (LTM) – Go Faster for Process Deviation: Fast Errors Detections on Large Surfaces Using Ellipsometry
- Giulio Vivo (CRF) – Digital Twin methodology for energy modelling and management of body and assembly shop floors
- Meirav Hadad-Segev (Brilliantor) / Alfio Minissale (COMAU) – Giving robots and machines human-like skills to collaborate
- Lior Yehieli (Applied Materials) – Next Generation Defect Inspection Computing Challenges



MADEin4

Thank You For Your Attention

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